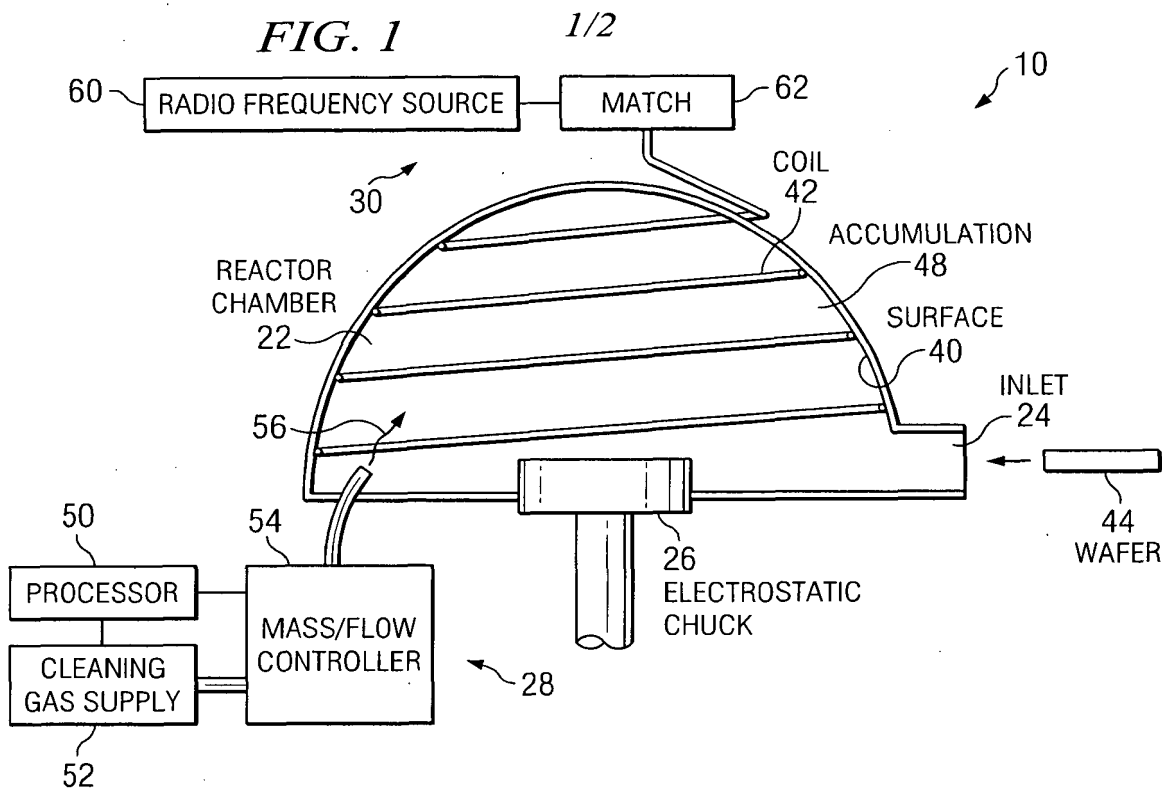


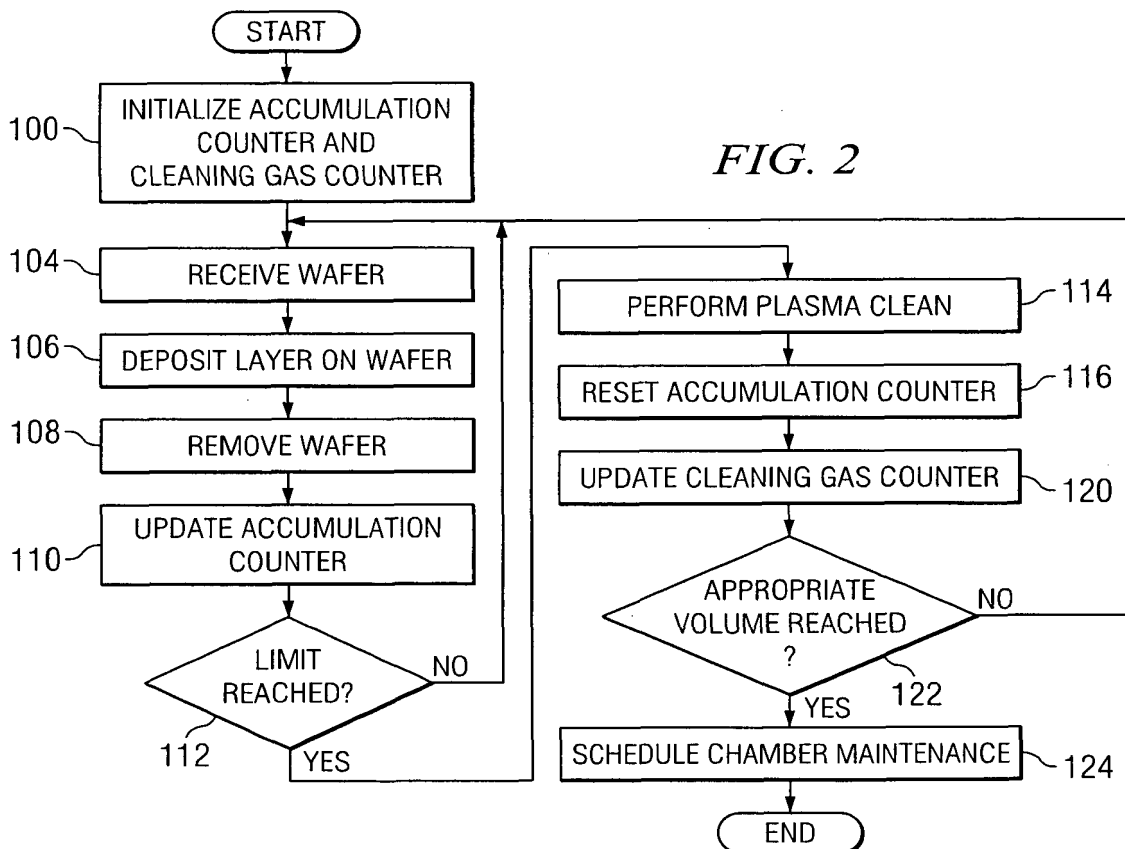
# MAINTAINING A REACTOR CHAMBER OF A CHEMICAL VAPOR DEPOSITION SYSTEM

Inventors: Jin (nmi) Zhao, et al. Atty Docket No. TI-35855 (032350.B505)  
Express Mail Label EV 324623873 US Page 1 of 2

**FIG. 1**



**FIG. 2**



# MAINTAINING A REACTOR CHAMBER OF A CHEMICAL VAPOR DEPOSITION SYSTEM

Inventors: Jin (nmi) Zhao, et al. Atty Docket No. TI-35855 (032350.B505)

Express Mail Label EV 324623873 US

Page 2 of 2

